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<th>Title</th>
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The Effect of Biasing the Plasma Electrode on Hydrogen Ion Formations in a Multicusp Ion Source

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The plasma electrode covered with magnetic cusp fields acting as a magnetic filter was installed in a multicusp ion source. The formation processes of the negative and positive hydrogen ions in this source have been investigated when an electrostatic positive bias is applied to the plasma electrode with respect to the anode chamber. The dominant H⁻ volume-production process is the recombinational attachment rather than the dissociative attachment when the bias voltage is more than +3 V. This recombinational attachment improves the H⁺ ratio in the extracted positive beam, keeping its current value.

KEY WORDS: Volume-produced H⁻ source/Plasma electrode biasing/Dissociative attachment/Recombinational attachment/Electron suppression

INTRODUCTION

The efforts towards extracting the volume-produced negative ions from various multicusp configurations with a magnetic filter have been made successfully. It has been indicated that the majority of extracted H⁻ ions is formed in the filter region by the dissociative attachment of low-energy electrons to vibrationally excited hydrogen molecules

\[ e + H_2(v^*) \rightarrow H^- + H. \]

The purposes of this work are to study the generation processes of hydrogen ions near the plasma electrode (PE) and to find the relationship between the plasma characteristics and the extracted ion currents. An ion source used in our experiment does not have a conventional magnetic filter but the beam extraction aperture is covered with cusp fields generated by permanent magnets installed in the PE. This magnetic field is named as the PE cusp. It is shown that this field configuration acts as a magnetic filter to enhance the H⁻ volume-production near the PE. We have investigated the PE bias effect on the generation processes in the presence of this cusp magnetic filter.

EXPERIMENTAL SET-UP

A schematic diagram of the experimental apparatus is shown in Fig. 1. The ion source
chamber is a cylindrical copper vessel (15cm in diameter by 22cm long) surrounded externally by ten columns of Sr–Ferrite magnets ($B_{\text{max}} \sim 1\text{Kg}$). These magnets from continuous line cusps parallel to the source axis and cusps are connected at the end plate by four extra rows of magnets. The open end of the chamber is enclosed by the two-electrodes extraction system. The first electrode (the PE) connected to the chamber is electrically isolated from the chamber wall to apply a bias voltage and has a beam extraction aperture (3mm in diameter). The chamber is biased at $-10\text{kV}$ relative to the second electrode (the beam extractor) at the earth potential when the negative ions generated in the discharge plasma are extracted. The polarity is reversed when the positive ions are extracted.

The ion source vessel, beam extraction systems and beam diagnostics are fabricated in a big vacuum chamber which is evacuated by a 1500/s turbo–molecular pump. The chamber can be evacuated to less than $5 \times 10^{-6}$ Torr before a neutral hydrogen gas is admitted to the system. The gas pressure in the chamber is monitored with a Penning Ion Gauge (PIG). A negatively biased 1mm in diameter and 100mm long tungsten filament is heated up with the current of about 60A. The filament power is adjusted to keep the arc current of 3A at the discharge voltage of 80V even if the neutral H$_2$ gas pressure is changed. A quiescent plasma with medium densities is obtained in a range of the pressure from 0.1m Torr to 10m Torr.

Pairs of Sr–Ferrite permanent magnets installed in the PE make magnetic cusp fields over
The Effect of PE Bias on Hydrogen Ion Formations

Fig. 2. The magnetic cusp field configuration near the PE.

Fig. 3. The profile of the transverse magnetic field induction on the z-axis near the PE. The arrow indicates the location of the beam extractor.

The magnetic cusp field is strong enough to keep the primary and energetic electrons from getting into the extraction region and the plasma is cold in this region. Thus, the field has the same effect as the conventional magnetic filter used to enhance the H⁻ volume-production. It divides the entire chamber into three regions as shown in Fig. 2. They are the extraction region (z≈0
cm), the filter region \((z \sim 2\text{cm})\) around the maximum cusp field, and the discharge region \((z \geq 4\text{cm})\) where most energetic electrons are confined and the electron temperature is rather high as described in the next section.

By means of an electron suppressor with permanent magnets, a reduction in the electron current extracted from an ion source has been reported\(^\text{20-22}\). The stray magnetic field over the beam extractor is strong enough to damp only electrons from the extracted beam while the ions are slightly deflected. The magnetic field configuration adopted here can eliminate the use of an electron suppressor.

The total extracted ion beam current is measured by a current detector of 200mm in diameter which has a 1mm wide and 20mm long slit in the center. After passing through the slit, a small fraction of charged particles enters a magnetic—deflection momentum analyzer and the mass distribution of the beam is obtained. It should be noted that a value of a specific ion beam current quoted in this paper is the product value of the total current and the ratio of the ion species.

We measure plasma characteristics by a movable cylindrical Langmuire probe\(^\text{43-46}\) (which is 3mm long and 1mm in diameter) to obtain profiles of the plasma electron density \(n_e\), the plasma electron temperature \(kT_e\), and the plasma potential \(V_p\). This probe is inserted into the chamber from the extraction aperture.

**EXPERIMENTAL RESULT**

**A. The effect of the PE cusp on plasma parameters**

Figure 4 shows the measured profile of the plasma parameters at two neutral gas pressures. The density of the discharge region \((z \sim 4\text{cm})\) with the PE cusp is two—times larger than that without the PE cusp since the magnetic cusp field over the PE confines the plasma effectively. Figure 4(a) also shows that the cusp field disturbs the plasma near the PE and causes

\[
\begin{align*}
\text{(a) Plasma electron density} & \quad \text{(b) Electron temperature} & \quad \text{(c) Plasma potential} \\
\end{align*}
\]

\[
\begin{align*}
\text{(a) Plasma electron density} & \quad \text{(b) Electron temperature} & \quad \text{(c) Plasma potential} \\
\end{align*}
\]

Fig. 4. The profiles of plasma parameters with the cusp field (solid lines) and without the cusp field (dotted lines) near the PE.
The Effect of PE Bias on Hydrogen Ion Formations

The electron density gradient.

Figure 4(b) shows that the plasma electron temperature around the PE cusp is lower and the plasma is cold \((kT_e \sim 1\text{eV})\) in the extraction region. Most of these cold electrons are attributed to diffusion processes across the magnetic field. The suitable plasma condition for the dissociative attachment process of \(H_2(v^+)\) is attained near the extraction aperture by this magnetic configuration.

B. The dependence of extracted currents on the pressure

The dependence of hydrogen ion yield on gas pressure is measured and the results are presented in Fig. 5. Figure 5(a) shows that the \(H^-\) yield increases rapidly with the source pressure up to 3mTorr. Above 3mTorr, the \(H^-\) current decreases slightly. The electron current exhibits a broad peak around the pressure of 0.5mTorr.

Figure 5(b) represents the variation of extracted positive ion currents. The dependence of the \(H^+\) and \(H^+_\) currents on the gas pressure in similar to that of the electron current. The \(H^+_\) current, however, has a peak of about 4\(\mu\)A at 0.3mTorr and decreases rapidly. This pronounced drop of \(H^+_\) with the increase of \(H^+_\) and \(H^+\) is probably caused by the higher rate of the resolution process of \(H^+_\),

\[
H^+_\ + H_2 \rightarrow H^+_\ + H,
\]

\[
H^+ + e \rightarrow H^+ + 2e.
\]

Figure 6(a) shows that the plasma density near the extraction aperture \((z=0\text{cm})\) is almost constant, while \(n_e\) in the filter and discharge region increases rapidly. The \(kT_e\), however, decreases remarkably at the pressure of 1mTorr and becomes almost constant \((\sim 1\text{eV})\) above 1mTorr (Fig. 6(b)). The increase of \(H^-\) ion current may be due to the drop of the electron temperature and the increase of the plasma density in the filter region. The results show that the optimum pressure is approximately 0.5mTorr for the \(H^+\) extraction and 3mTorr.
for the $^-$ extraction with the arc power of 80V 3A.

C. The extracted current as a function of the PE bias voltage $V_b$

The $^-$ yields as a function of the PE bias voltage at four neutral gas pressure are shown in Fig. 7. A small positive bias potential relative to the anode enhances the $^-$ yield accompanied with a reduction of the electron current. At each pressure, an optimum $^-$ yield is obtained at the PE bias between $+1$V and $+3$V relative to the anode. The enhancement of the $^-$ yield is more noticeable when the pressure is about 0.5mTorr. The dependence of the
The Effect of PE Bias on Hydrogen Ion Formations

H\(^-\) current on \(V_b\) was examined at the pressure of 0.7mTorr at which the H\(^-\) yield exhibits the most enhancement and the result is shown in Fig. 8.

The extracted H\(^-\), current, \(I_\text{e}\), has a peak of 9\(\mu\)A at \(V_b=+1\)V. The extracted electron current \(I_\text{e}\) is about 1.5mA at \(V_b=0\)V and it decreases to about 0.1mA at \(V_b=+2.5\)V. Thus, by employing the PE cusp and biasing the plasma electrode at +2.5V, the ratio of \(I_\text{e}/I_\text{e}\) was improved from 1/250 to 1/15.

Figure 8(b) shows the ratio of positive ion species as a function of \(V_b\). The \(H^+\) and \(H^+\) currents decrease steeply as \(V_b\) is increased. Figure 8(b) shows that the rather high \(H^+\) ion percentage is obtained at higher \(V_b\) than +4V with slight decrease of its current value.

The plasma electron density \(n_e\), the plasma potential \(V_p\) and the electron temperature \(kT_e\), are measured as a function of \(V_b\) and the results are shown in Fig. 9. It is illustrated in Fig. 9 (a) that \(n_e\) in the filter region decreases more rapidly than that in the discharge region. With the small positive bias, there is a large drop in density at the filter region. This corresponds to the decrease of the extracted electron current. Figure 9(b) shows that \(kT_e\) increases with \(V_b\) particularly in the filter region. These variations of \(n_e\) and \(kT_e\) reduce the rate of the dissociative attachment and decrease the H\(^-\) current. Comparing Fig. 9(b) and Fig. 7, it is found that \(kT_e\) in the filter region (\(z\sim2\)cm) is always about 0.8eV when \(I_-\) exhibits the maximum current. It can be also seen in Fig. 9(b) that \(kT_e\) in the filter region becomes close to or higher than that in the discharge region when the \(H^+\) ion is the dominant component in the extracted positive ion current. This phenomenon is related to the recombinational attachment and the detail discussion is shown in the next section.

The important result is that the negative ion production is enhanced when the electron temperature in the filter region is about 0.8eV with either change of the neutral gas pressure or \(V_b\). The effect of \(V_b\) on the electron density \(n_e\) and the electron temperature \(kT_e\) is weak at the discharge region (\(z\geq4\)cm). The major part of the plasma volume is not affected by \(V_b\).

The extracted ions are strongly affected by the plasma condition of the filter region. These results indicate that most of the extracted ions are produced in the filter region.

(67)
The observed $H^-$ yield at a low electron temperature is consistent with either the dissociative attachment of $H_2^+(v')$ or the recombinational attachment of molecular hydrogen ions.\textsuperscript{15}) It has, however, reported\textsuperscript{8}) that the dominant $H^-$ production process in filter-equipped multi-cusp sources is the dissociative attachment. In our experiments, the optimum $H^-$ production is obtained when the plasma electron temperature in the filter region is about 0.8 eV. The same result has been reported in Ref. 2.

It has been also indicated\textsuperscript{5}) that the elimination of a potential gradient between the PE and the source plasma plays an important role in the $H^-$ yield when a small positive bias is applied to the PE. Figure 9(c) shows that the difference between the plasma potential and the PE bias, $V_p-V_b$, is reduced from about 2V (for $V_b=0$V) to about 1V (for $V_b=2$V). The plasma potential is almost constant throughout the extraction region and the discharge region at this $V_b$ value. The enhanced $H^-$ yield by the small PE bias can be explained by both effects.

Figure 9(b) shows that the electron temperatures in the filter region increase up to 1.5eV with $V_b$. Energetic electrons mainly emitted from the filament are winding around magnetic cusp field lines.\textsuperscript{49}) When the PE bias is applied, those electrons will $E \times B$ drift vertically in a cycroidal motion and electrons trapped in the filter field becomes more energetic. These electrons may contribute to the rise in electron temperatures which decreases the rate of the dissociative attachment. Figure 8(a), however, shows that the remarkable tail of the $H^-$ yield at higher $V_b$. The rate of the recombinational attachment,

$$e + H_2^+ \rightarrow H^- + H^+,$$
$$e + H_3^+ \rightarrow H^- + H_2^+,$$

increases gradually as the electron temperature becomes high because this process has a
The Effect of PE Bias on Hydrogen Ion Formations

maximum cross section in the energy range of 4eV to 10eV. Most of H$^-$ ions seems to be formed by the recombinational attachment when $V_b$ is more than +3V.

Figure 8 shows that the extracted H$^+$ ion current is comparable to the H$^-$ current with decrease of the H$_2^+$ and H$_3^+$ ions when $V_b$ is more than +4V. The H$^+$ yield probably comes from the dissociation of molecular ions, H$_2^+$ and H$_3^+$. This also indicates that the recombinational attachment is predominant over the dissociative attachment at $V_b$ higher than +3V.

Summarizing the above results, it is shown that the dominant H$^-$ formation process changes with PE bias and the ratio of positive ion species is sensitive to the PE bias values.

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